

Optical Frequency Topological Photonic Structures

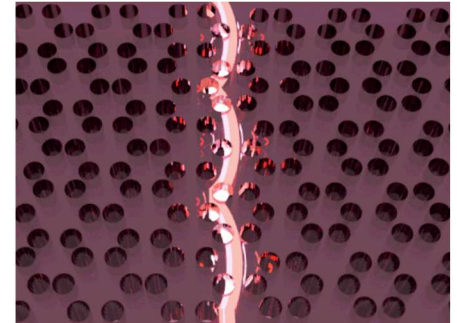
Ganapathi Subramania

Sandia National Laboratories, Albuquerque, NM

Collaborators: P. Duke Anderson(SNL), Daniel D. Koleske(SNL), Jason Dominguez and Anthony James and Stavroula Foteinopoulou (Univ. of NM)

November 19-23, 2018

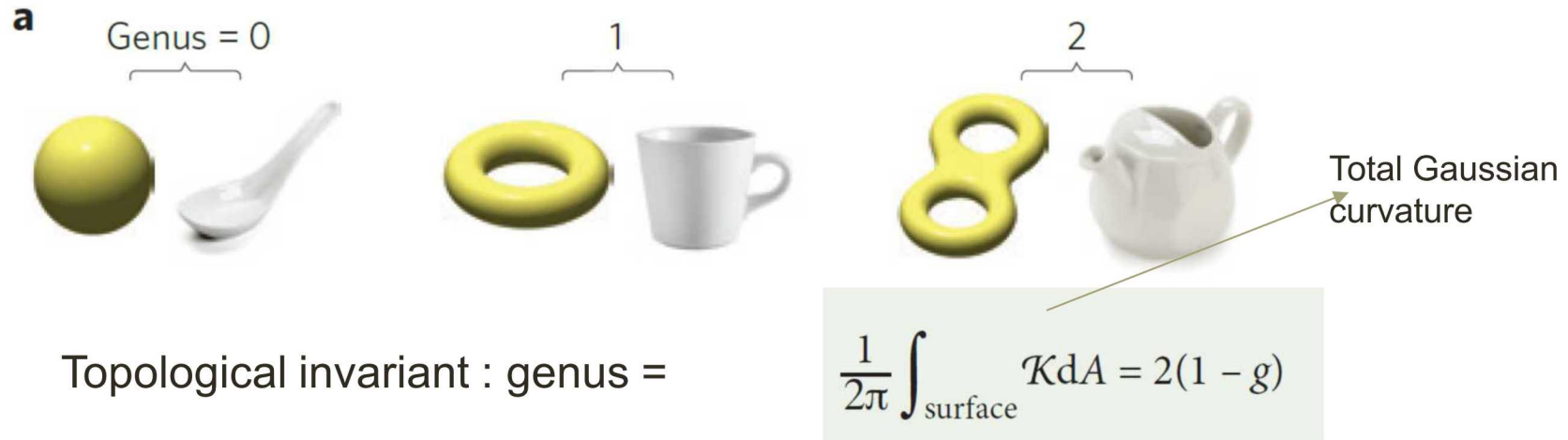
Material Research Society Fall 2018,
Boston, MA, USA



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Topological Protection

Topological Protection: Approaches that exploit topological properties of the phase space of a system can offer stability and robustness to the system of interest from external disturbances such as scattering, decoherence etc.



- Need to create a topological transition to affect the system.

➤ Non-trivial topological system can provide new ways of control in electronics and **photonics**. (Eg. Loss-less unidirectional, scatter-free transport)

L. Lu, J. D. Joannopoulos, and M. Soljacic, "Topological photonics," Nat Photon **8**, 821-829 (2014).

Topological Photonics Research Activities

PHYSICAL REVIEW A 78, 033834 (2008)

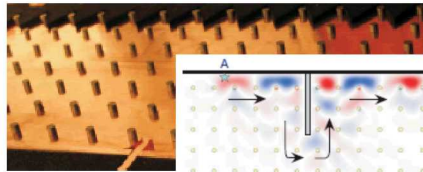
Analogs of quantum-Hall-effect edge states in photonic crystals

S. Raghu*

Department of Physics, Stanford University, Stanford, California 94305-4045, USA

F. D. M. Haldane

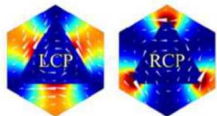
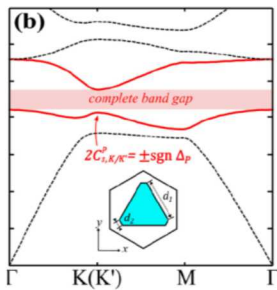
Department of Physics, Princeton University, Princeton, New Jersey 08544-0708, USA



One-way transport at microwave frequency

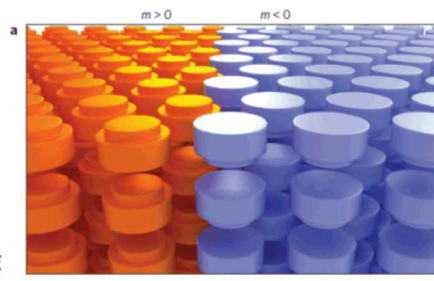
Z. Wang, Y. Chong, et.al., Nature **461**, 772 (2009).

Valley hall PTI



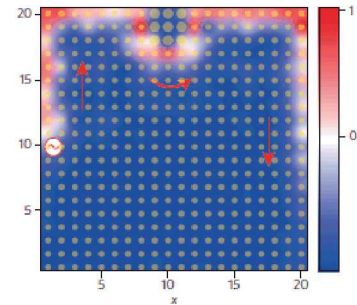
M. Tzhusuan and S. Gennady, NJP. **18** (2), 025012 (2016).

3D All dielectric PTI



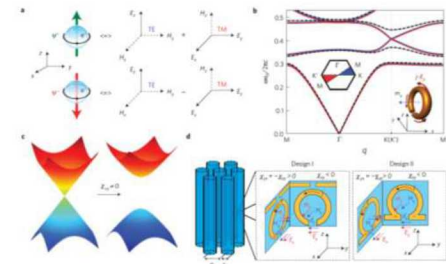
A. Slobozhanyuk, et.al., Nat Photon **11** (2), 130-136 (2017).

One-way edge transport



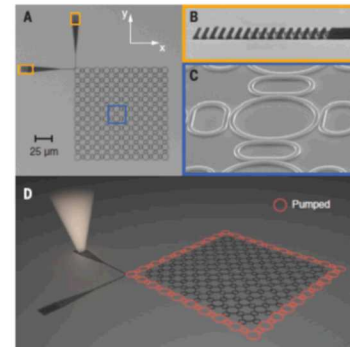
K.Fang, Z. Yu, S.H.Fan, Nat. Phot. **6**, (2012)

Metamaterial PTI



A. B. Khanikaev et.al. Nat Mater **12** (3), 233-239 (2013).

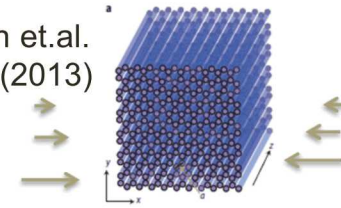
PTI lasing



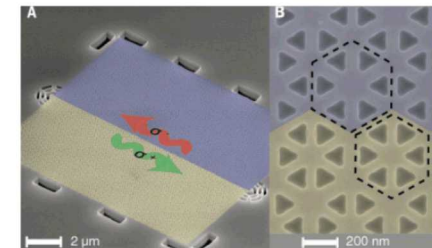
Bandres, M. A. et al. Science **359**, eaar1231 (2018).

Strain induced pseud mag. field in optical fiber arrays

M.Rechtsman et.al. Nat. Phot. **7** (2013)



Topological edge states in III-V



Barik, S. et al.. Science **359**, 666 (2018).

Outline

- Pseudo spin based all dielectric topological structure
- Fabrication approach
 - Silicon-on-insulator fabrication
- Approaches for III-nitride based active PTI
- Summary

Topological Photonics Spin Hall in Dielectric PC

PRL 114, 223901 (2015)

PHYSICAL REVIEW LETTERS

week ending
5 JUNE 2015

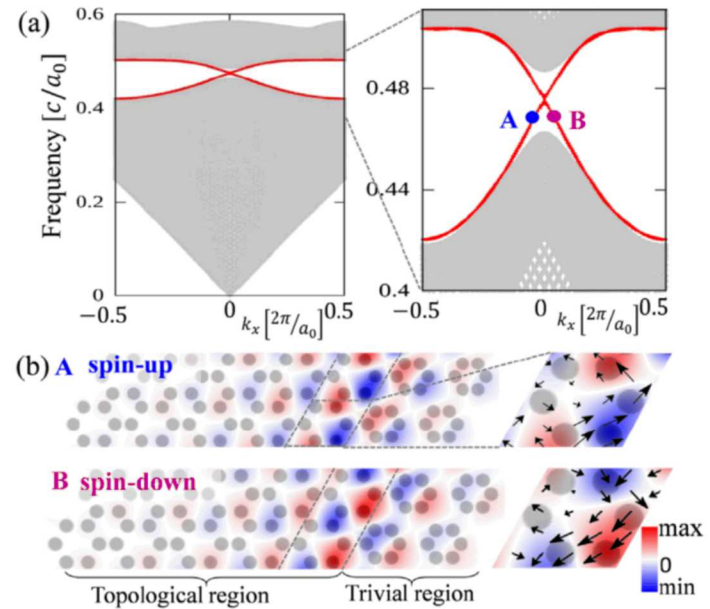
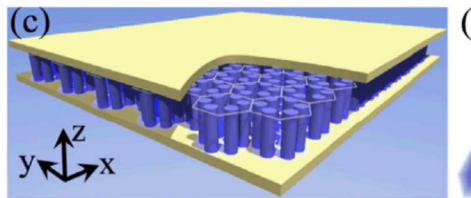
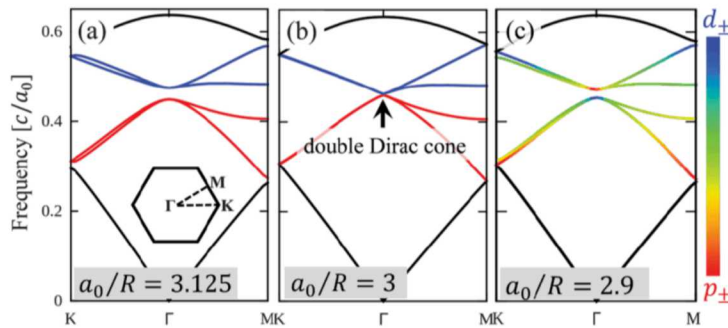
Scheme for Achieving a Topological Photonic Crystal by Using Dielectric Material

Long-Hua Wu and Xiao Hu*

*International Center for Materials Nanoarchitectonics (WPI-MANA), National Institute for Materials Science,
Tsukuba 305-0044, Japan*

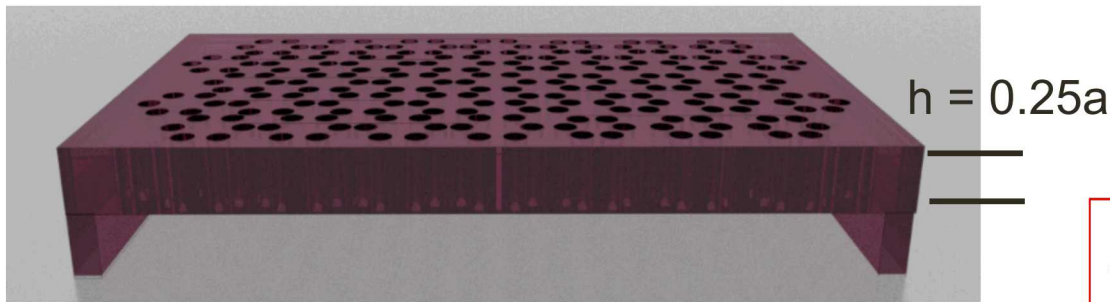
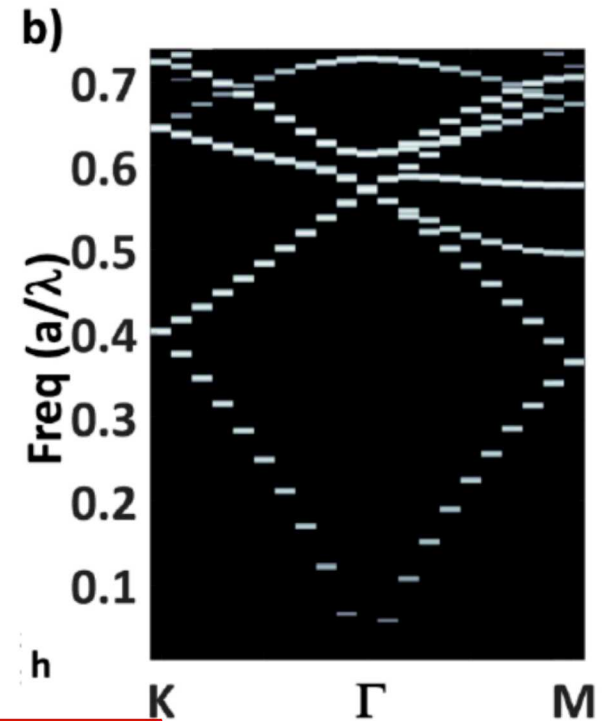
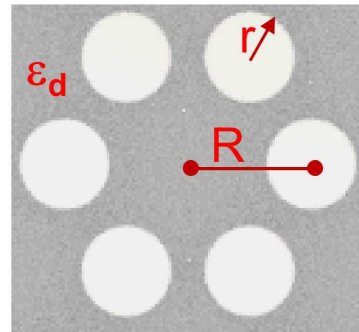
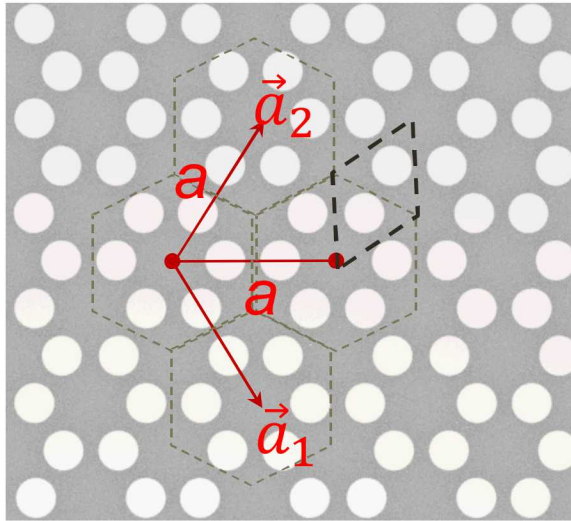
Graduate School of Pure and Applied Sciences, University of Tsukuba, Tsukuba 305-8571, Japan

(Received 10 February 2015; published 3 June 2015)



Modified honeycomb lattice of hexagonal cylindrical dielectric rods

Thin-slab Photonic Crystal Design



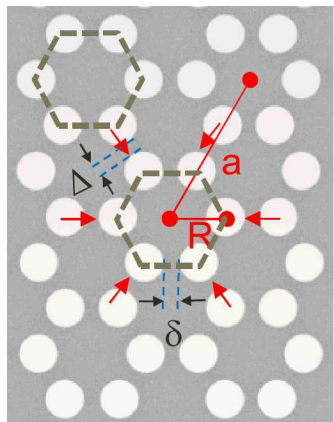
$$a/R = 3.0$$

$$r = 0.13a$$

Calculated with FDTD (Lumerical®)

Circular Hole Array Honeycomb Lattice Photonic Crystal

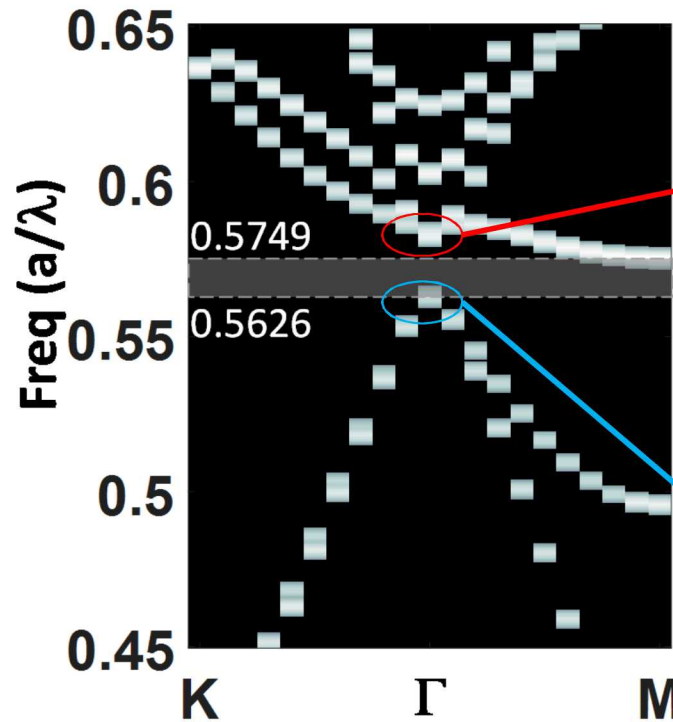
Compressed lattice $a/R = 3.1$



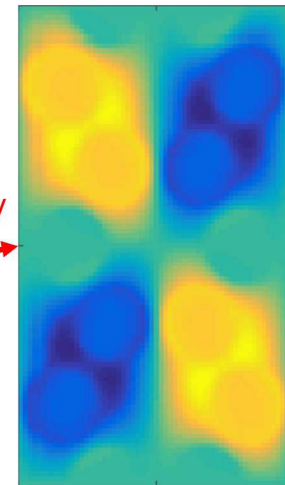
$$\Delta = a - 2(R + r)$$

$$\delta = R - 2r$$

Topologically Trivial PC



d_{xy}

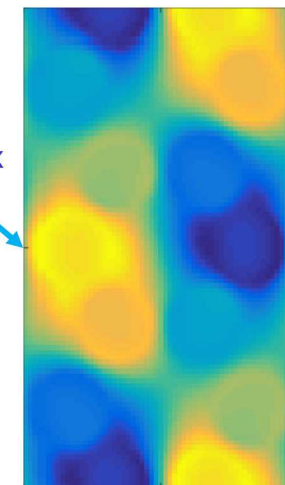


Re(Hz)

Max

Min

p_x

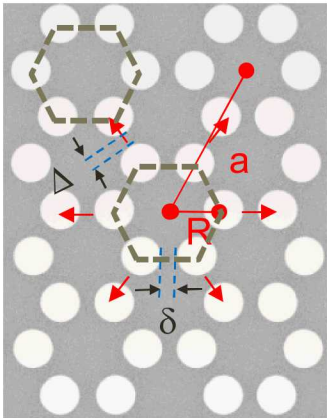


Max

Min

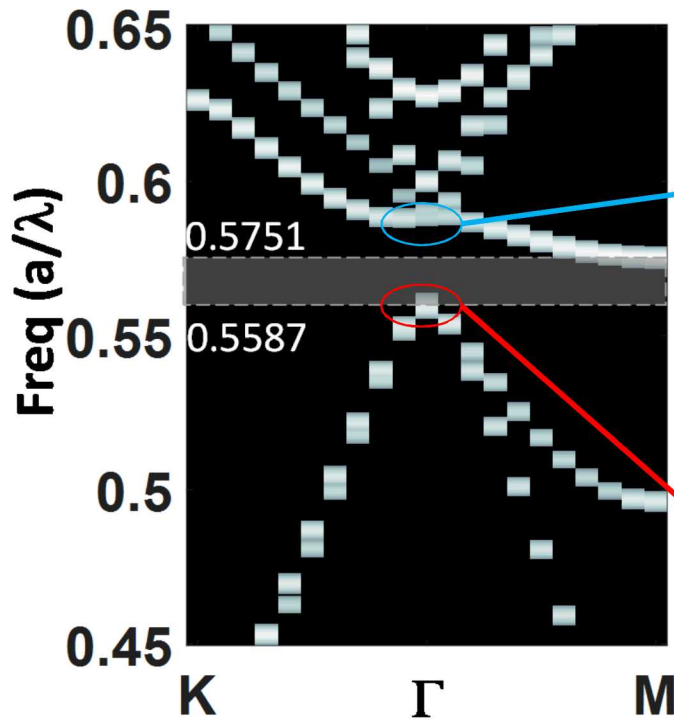
Circular Hole Array Honeycomb Lattice Photonic Crystal

Expanded lattice $a/R = 2.9$

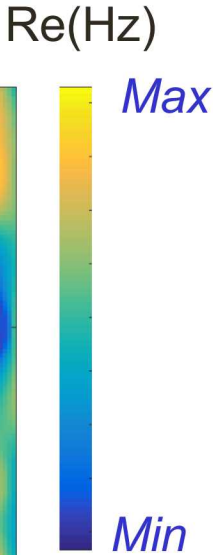
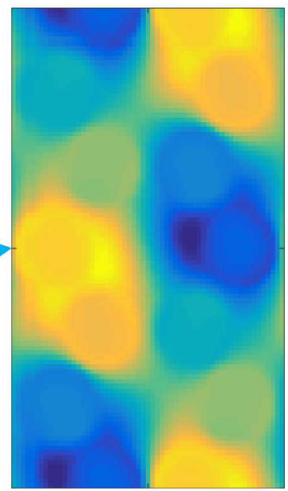


$$\Delta = a - 2(R + r)$$

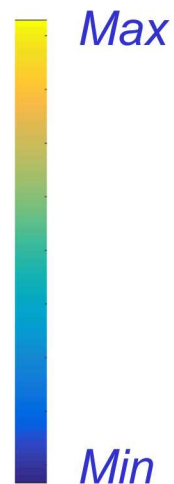
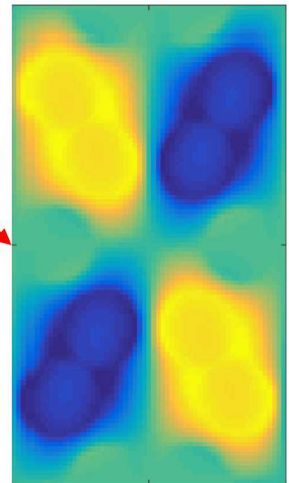
$$\delta = R - 2r$$



p_x



d_{xy}



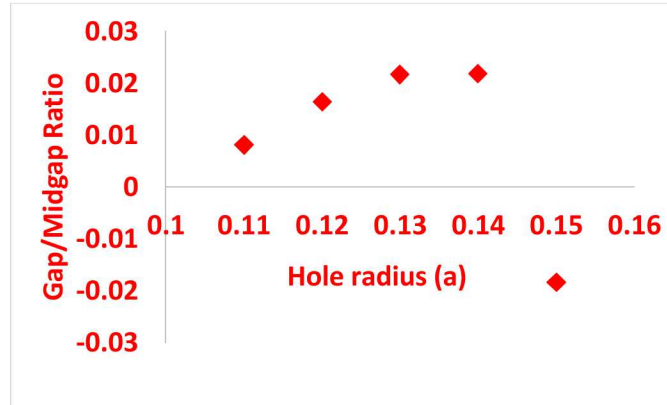
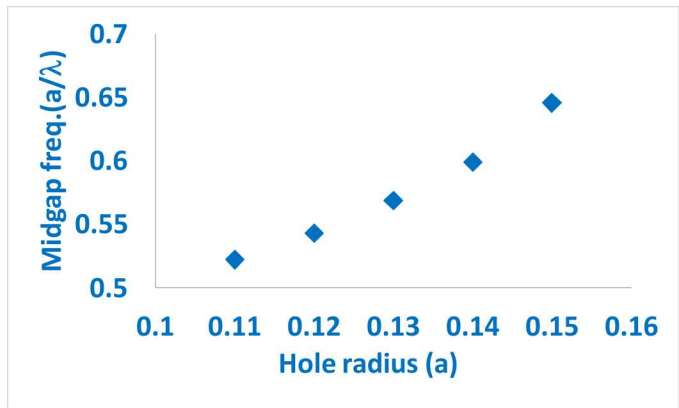
Topologically Non-trivial PC

Circular Hole Array Honeycomb Lattice Photonic Crystal

Hole radius 'r' dependence

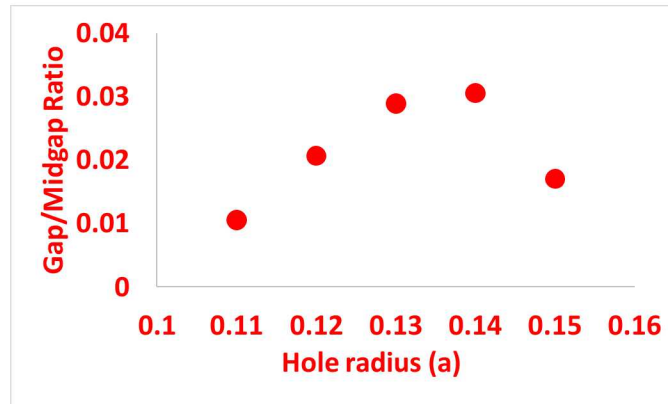
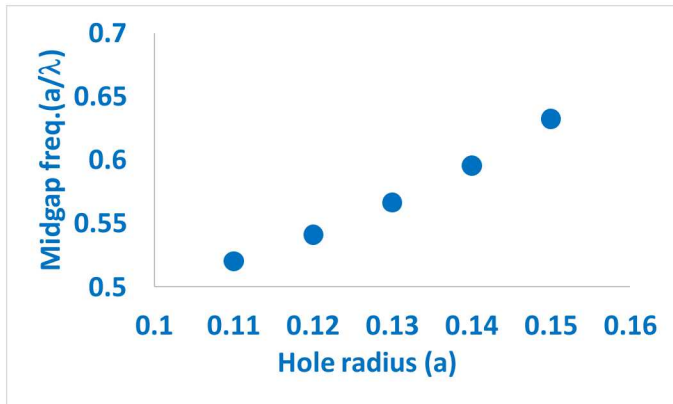
Compressed $a/R = 3.1$

Membrane thickness
'h' = 0.25a



At $\lambda \sim 1500\text{nm}$
 $\Delta\lambda \sim 30\text{nm}$

Expanded $a/R = 2.9$

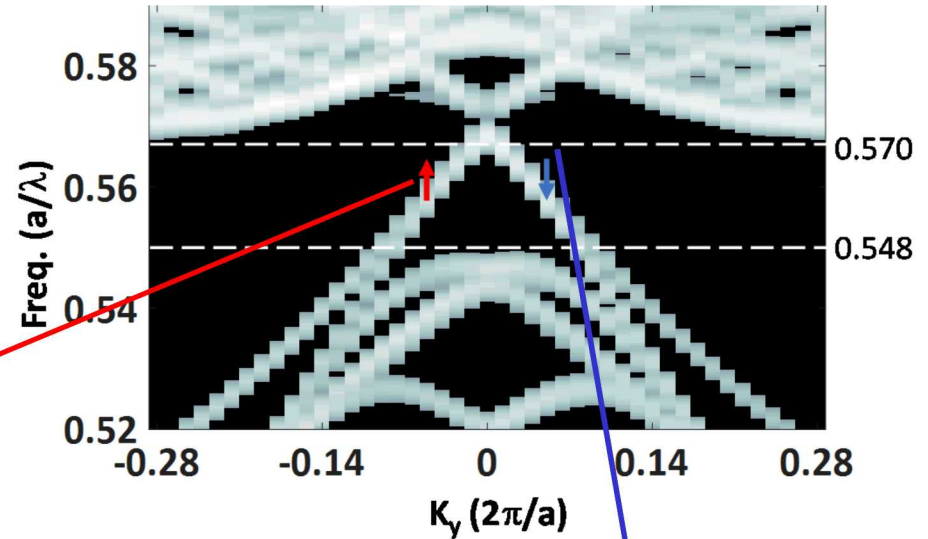
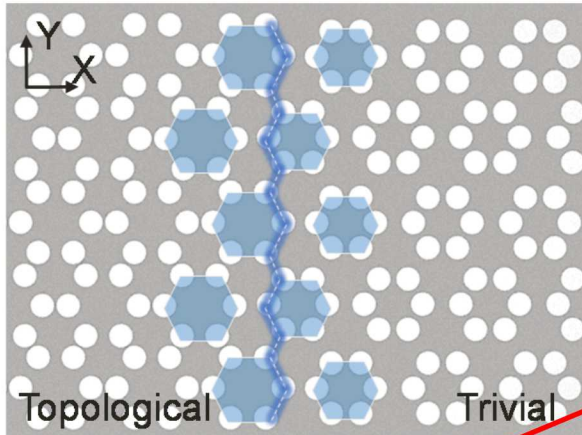


At $\lambda \sim 1500\text{nm}$
 $\Delta\lambda \sim 45\text{nm}$

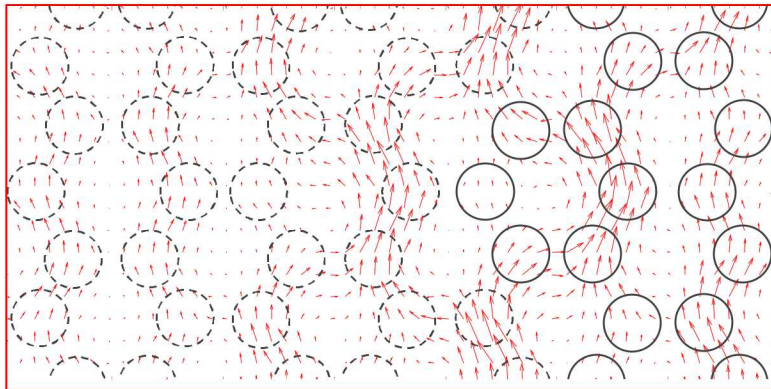
Reasonable operational bandwidth possible at the telecom frequencies

Unidirectional Edge State Propagation

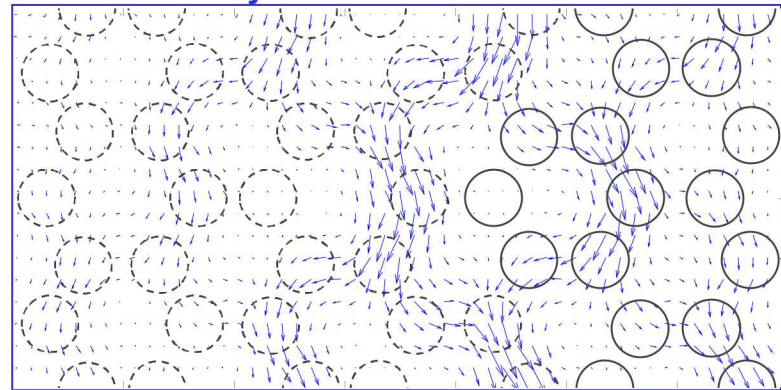
Zig-zag interface



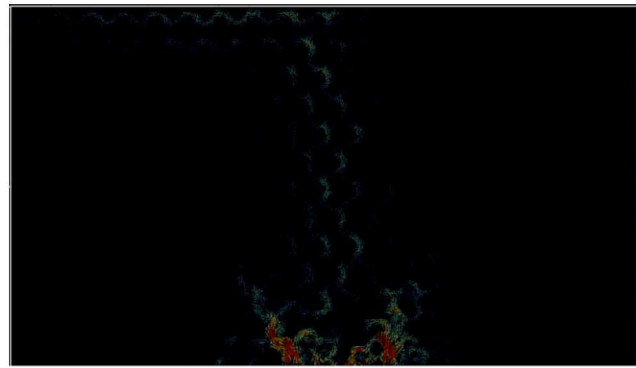
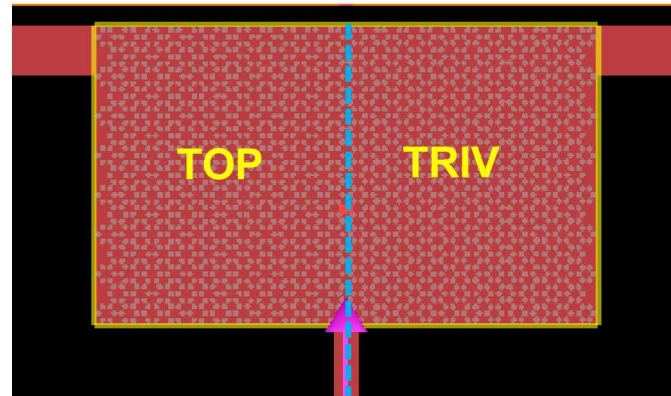
$$k_y = -0.05(2\pi/a)$$



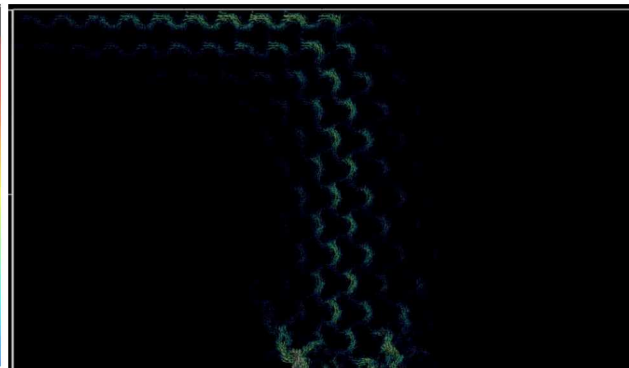
$$k_y = 0.05(2\pi/a)$$



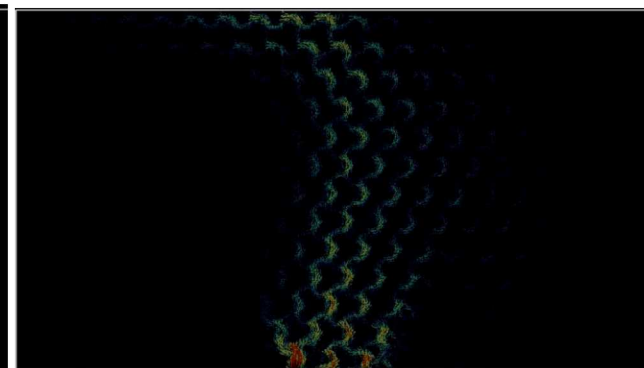
Demonstrating Topological Behavior in a Waveguide System



$a/\lambda \sim 0.557$



$a/\lambda \sim 0.552$

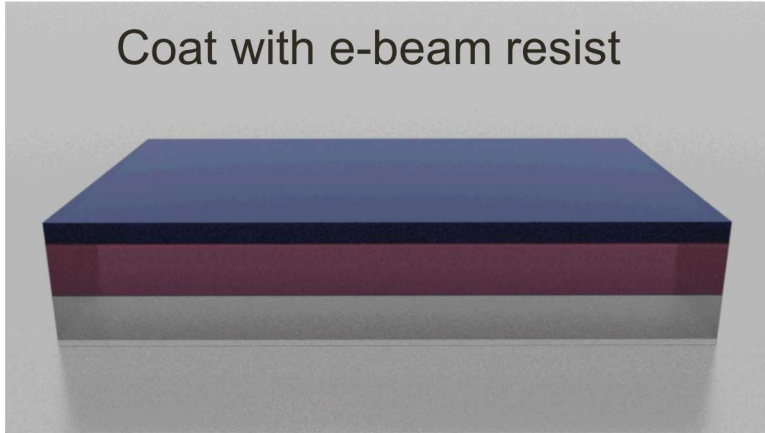


$a/\lambda \sim 0.543$

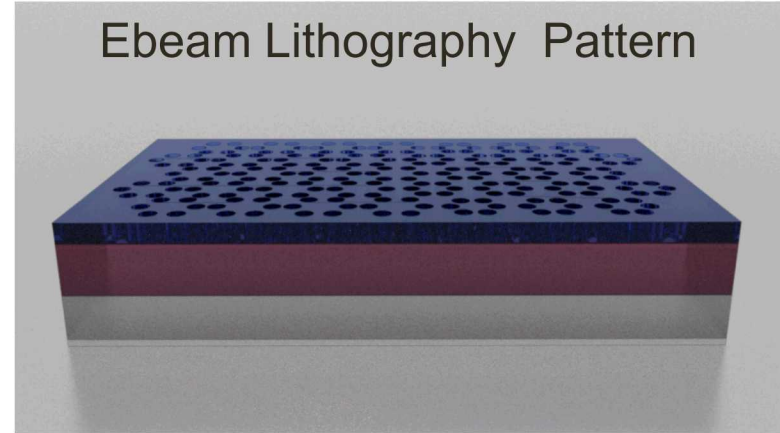
- This can be implemented experimentally
- Can observe the bandwidth of top. behavior

Fabrication on Silicon on Insulator (SOI) - Membrane

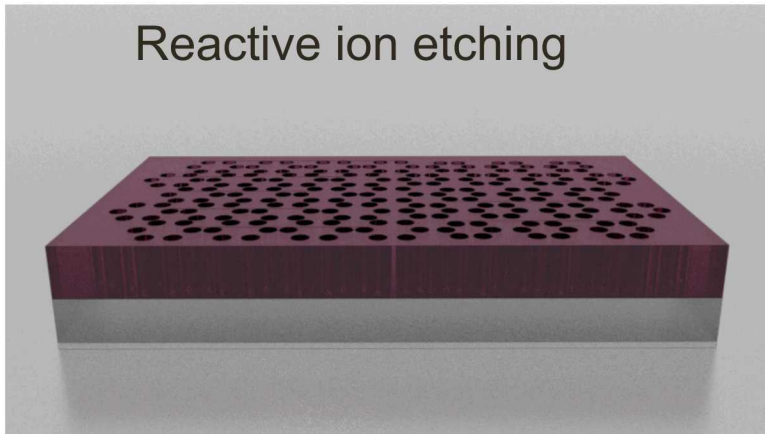
Coat with e-beam resist



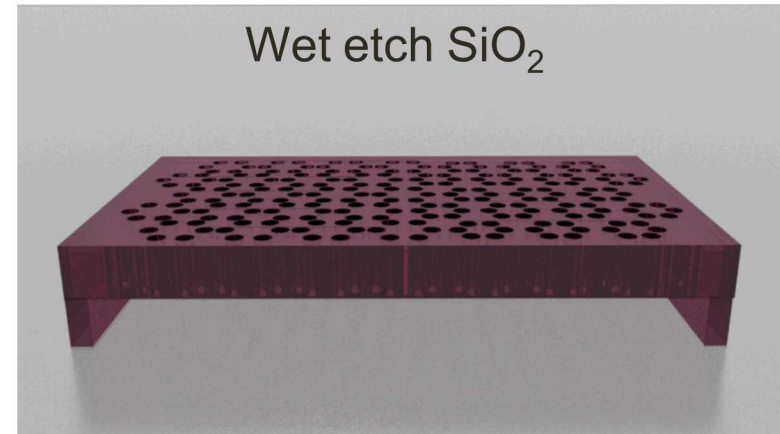
Ebeam Lithography Pattern



Reactive ion etching



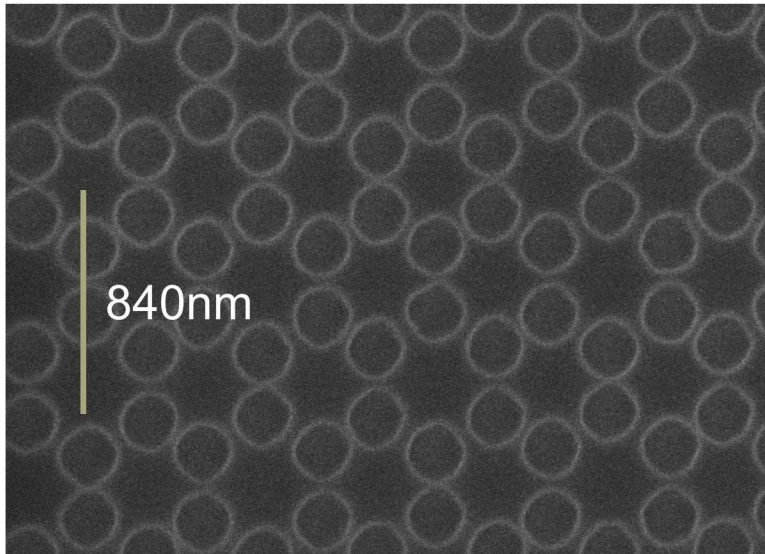
Wet etch SiO₂



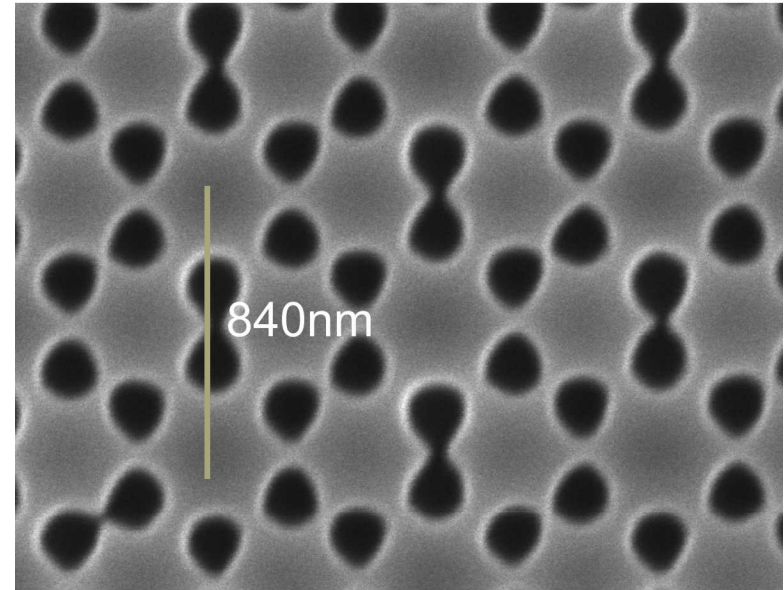
Fabrication on Silicon on Insulator (SOI) - Membrane

- For $\lambda \sim 1500$ operation $a \sim 840\text{nm}$
- Hole radius 'r' = $0.13 \cdot 840 = 110\text{nm}$ or 'd' $\sim 220\text{nm}$
 - Typical feature sizes at the necks $\sim 30\text{-}50\text{nm}$

After pattern write in resist



After pattern transfer

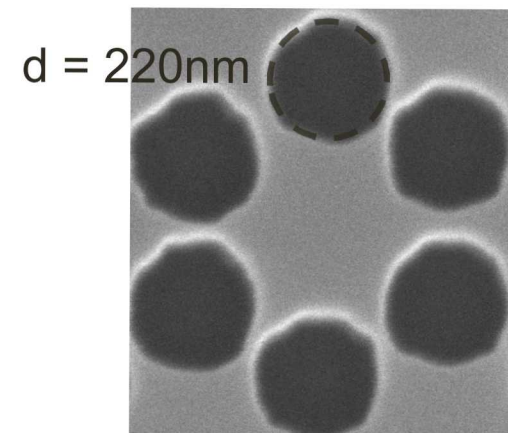
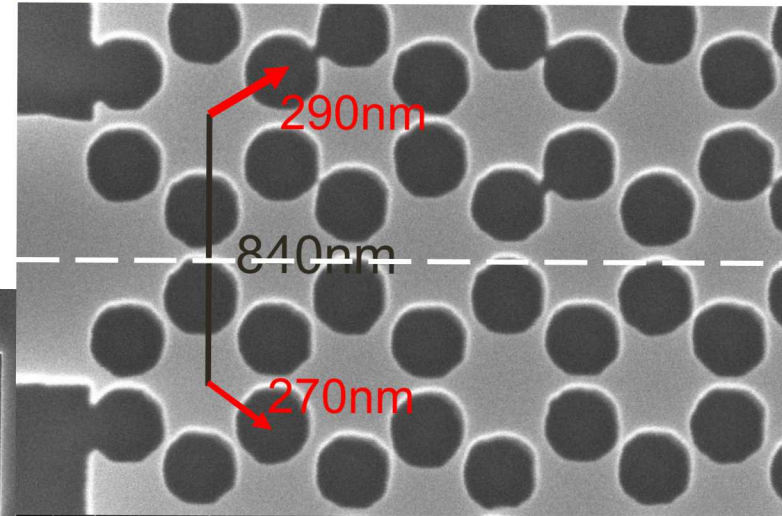
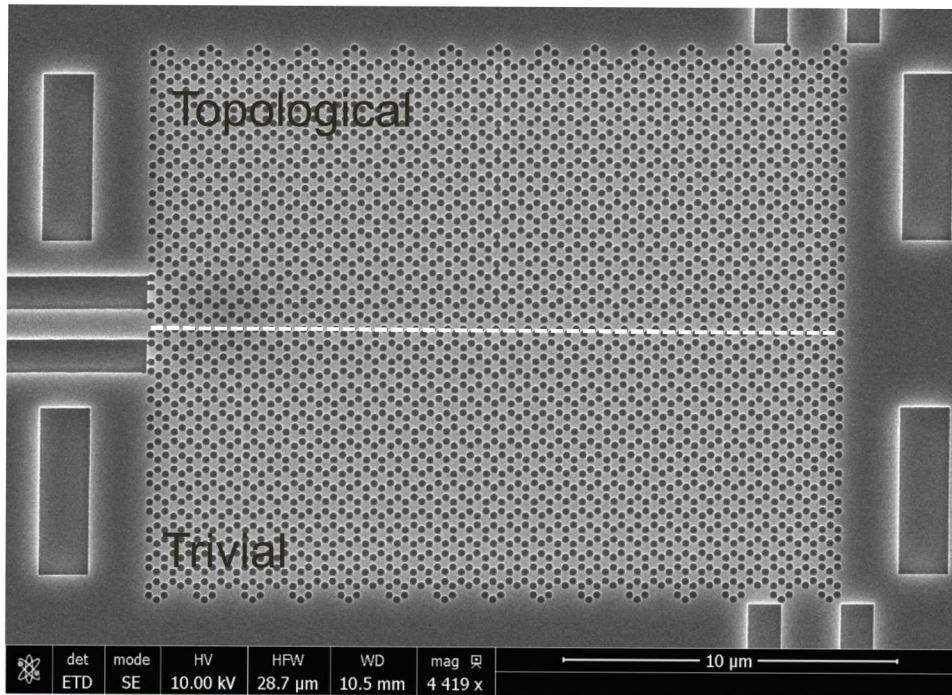


Issues with 'necking' of adjacent holes - addressed with SiO₂ hard mask

Fabrication on Silicon on Insulator (SOI) - Membrane

Pattern transfer to Si

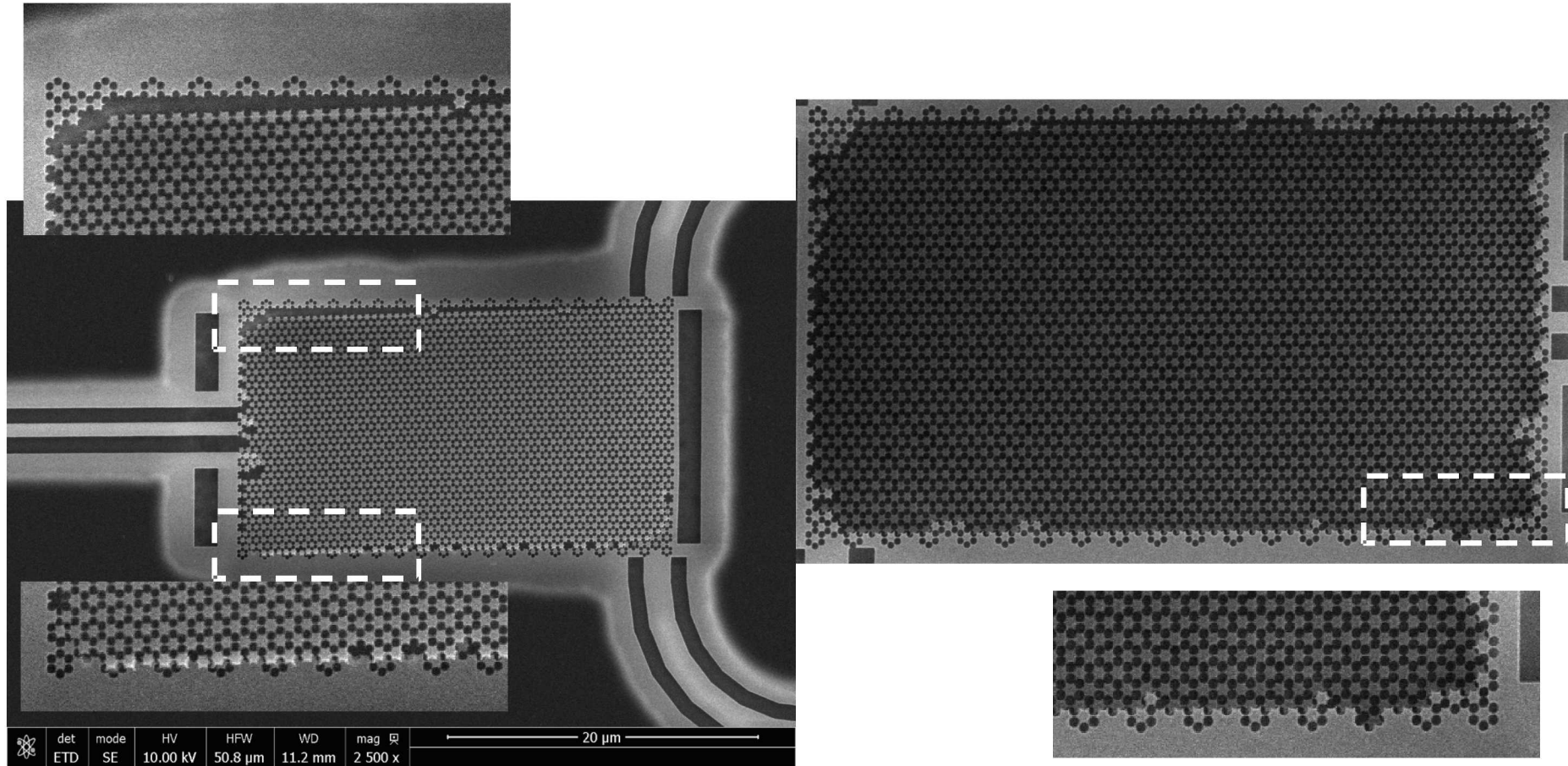
- ~ 50 nm SiO₂ is used as hardmask for pattern transfer
- Highly selective HBr based RIE for Si etch



Fabrication on Silicon on Insulator (SOI) - Membrane

Release etch for membrane

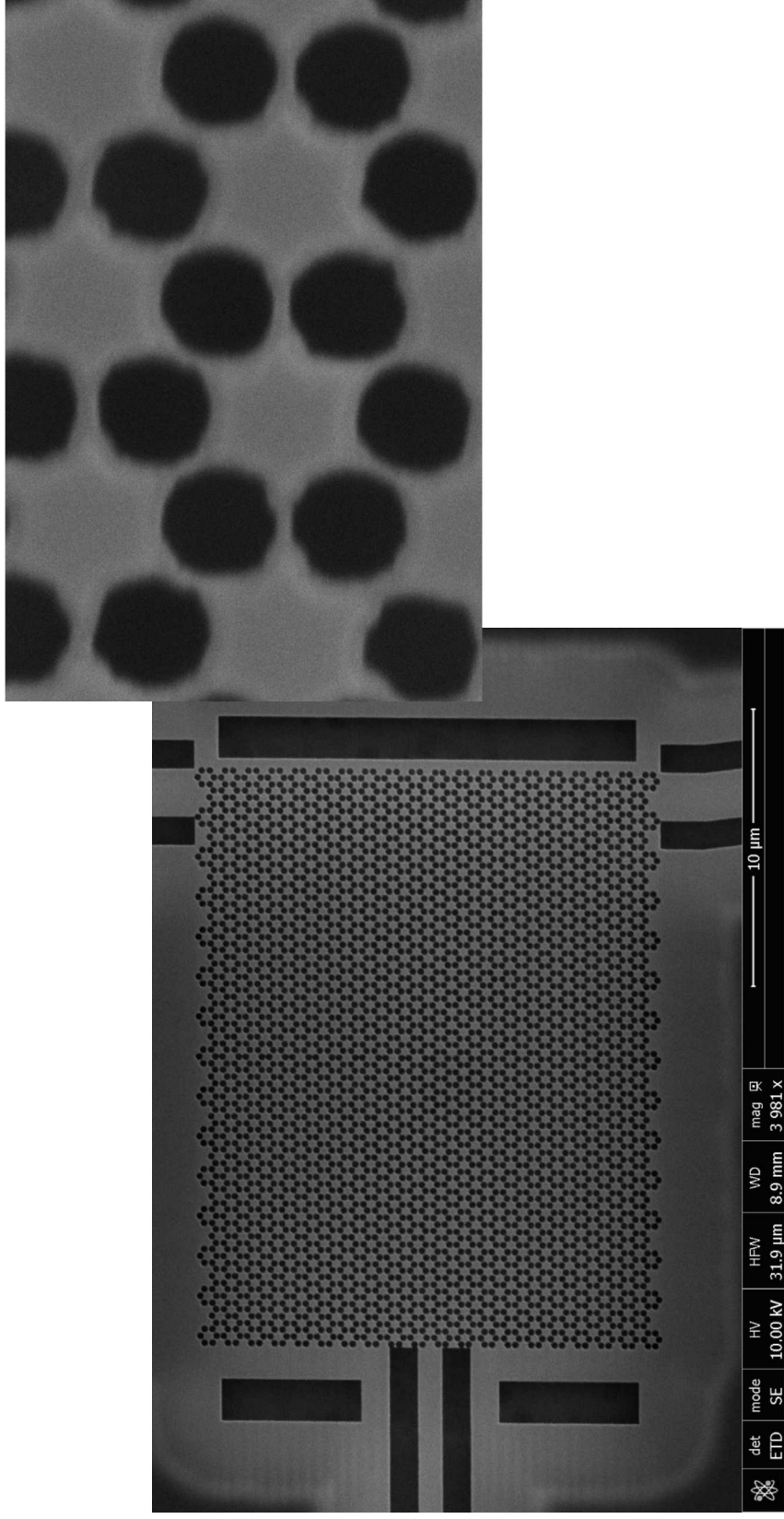
- Wet etch in buffered oxide etchant for 15-20min : 1.6 to 1.8 μm deep
- Narrow bridge necks + Si epi stress causes some challenges



Fabrication on Silicon on Insulator (SOI) - Membrane

Release etch for membrane

- Reduced etch depth to $\sim 1.0 \mu\text{m}$ shows improvements

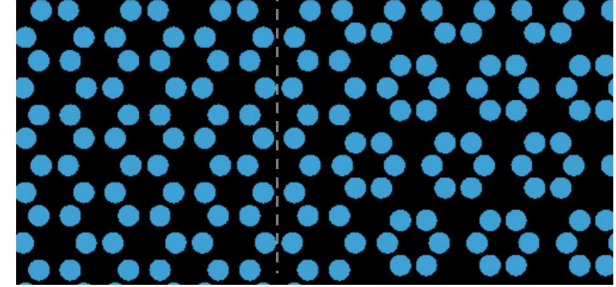
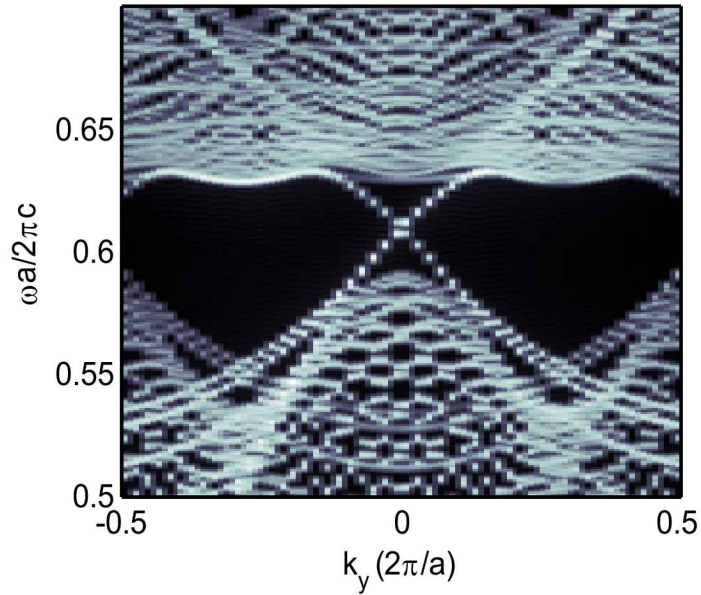


III –nitride based structures for Active Topological PhCs

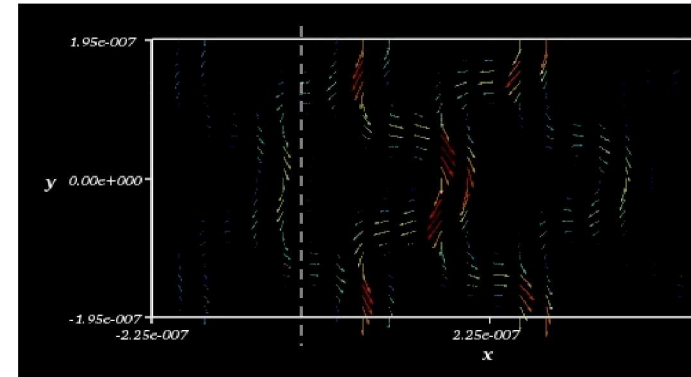
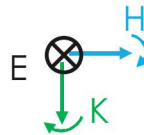
Topological edge state in honeycomb lattice structure in III-Nitride

Modeling

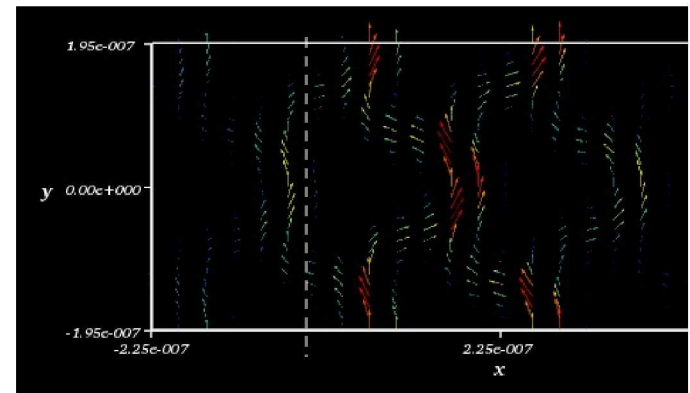
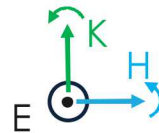
Band Structure



Spin-down state
 $a/\lambda = 0.618$

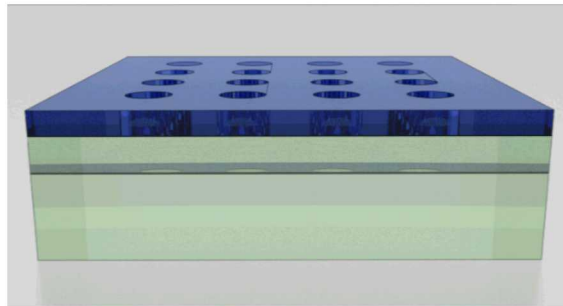


Spin-up state
 $a/\lambda = 0.60$

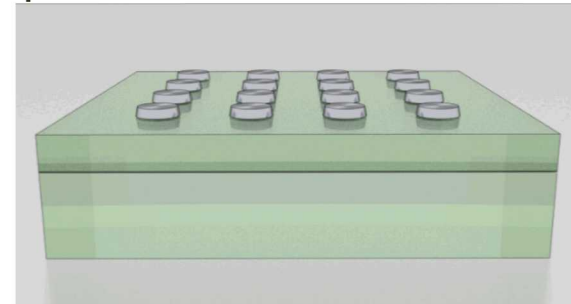


Fabrication procedure in GaN

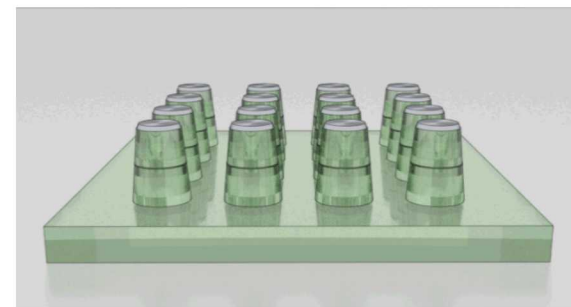
EBL pattern in PMMA



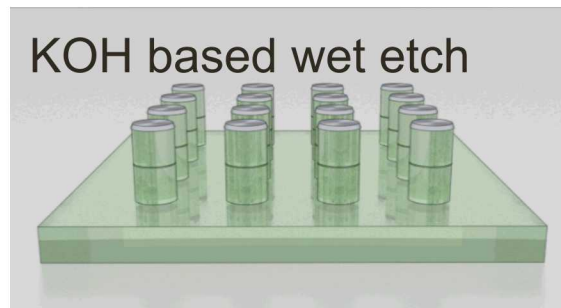
Ni evaporation and lift-off



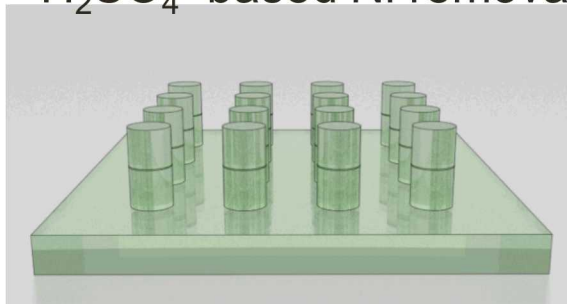
Cl₂ based dry etch



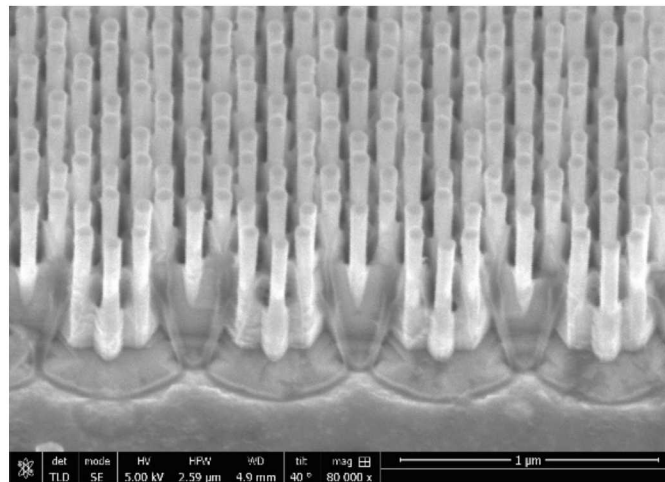
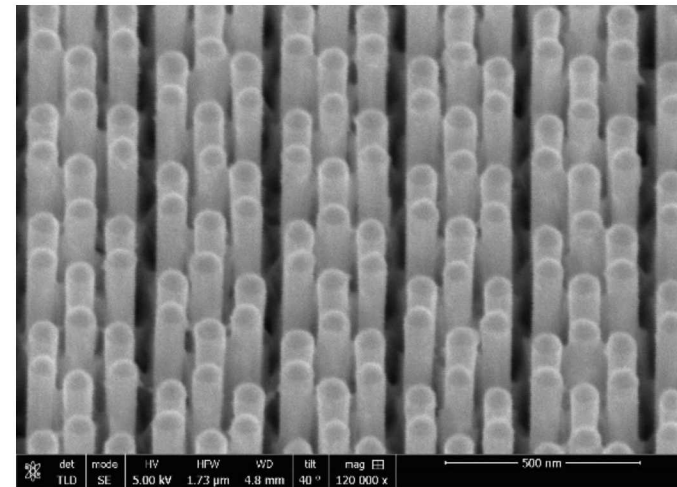
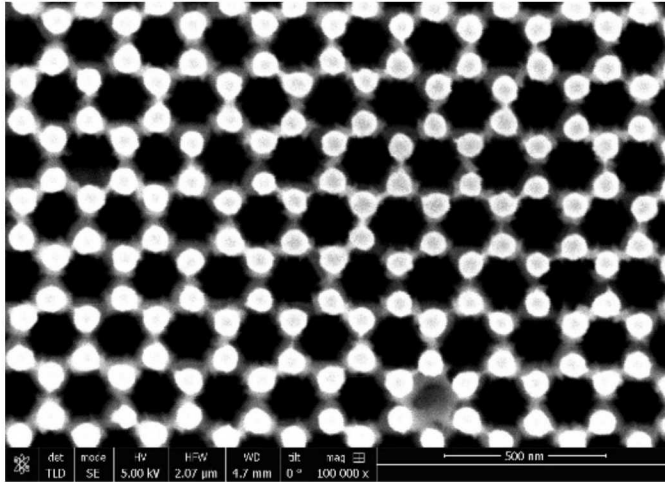
KOH based wet etch



H₂SO₄-based Ni removal



Topological/Trivial lattice interface structure in III-Nitride



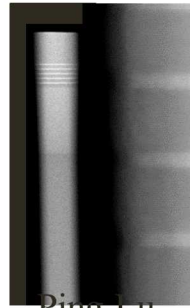
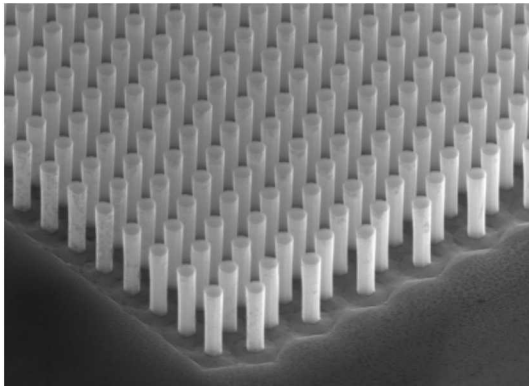
Ongoing ...

- Main challenges
- Deeper etching

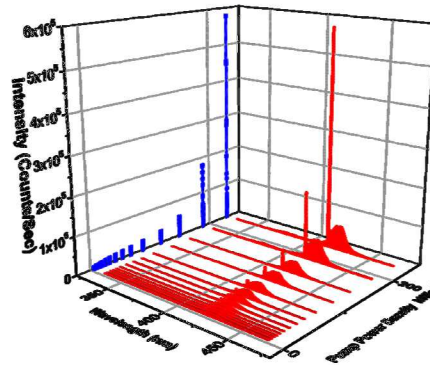
Topological structure in active material systems

PhC nanrod array have shown excellent light emission behavior

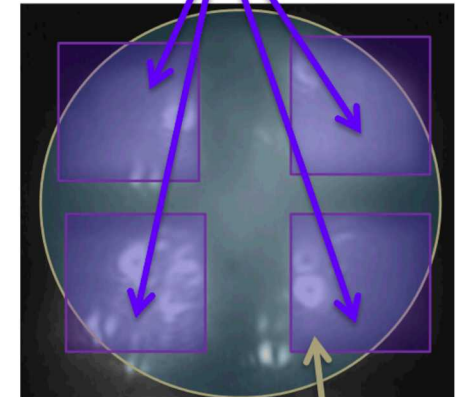
Demonstration of Lasing from PhC Array



Ping Lu,
Sandia



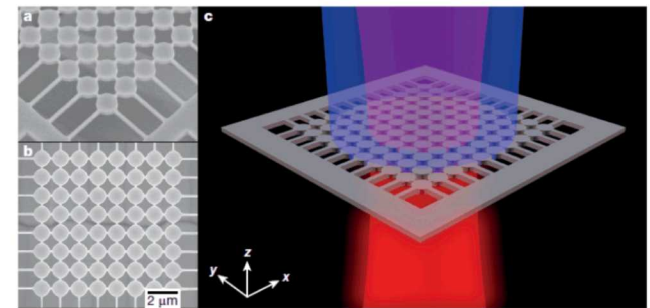
Photonic Crystal Laser Pixels



Pump Spot

J. B. Wright et al., *Sci. Rep.* **3**, 2982 (2013).

Fabricated by using a top down approach from a planar GaN with InGaN Multiple quantum wells

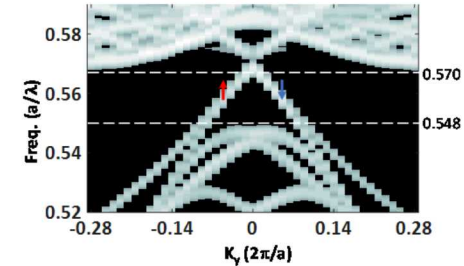
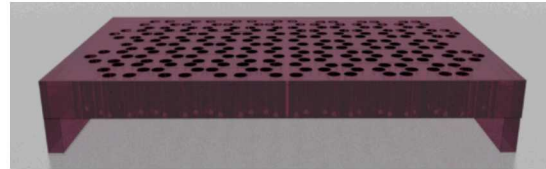


A. Kodigala, et al., *Nature* **541**, 196-199 (2017).

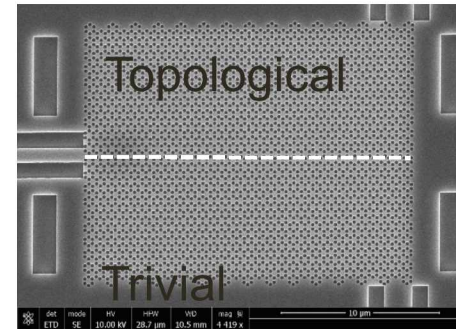
Light sources with topological charges?

Summary

- Hole array honey comb lattice structure for photonic pseudo spin

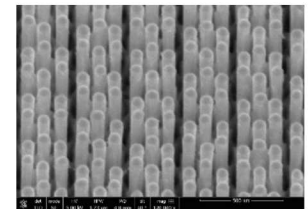


- Fabrication in Silicon/SOI



- Next ... Optical measurement

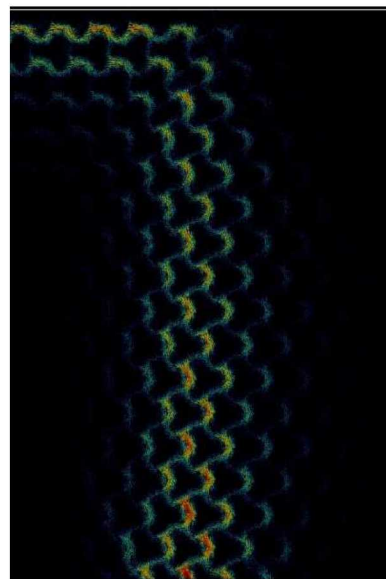
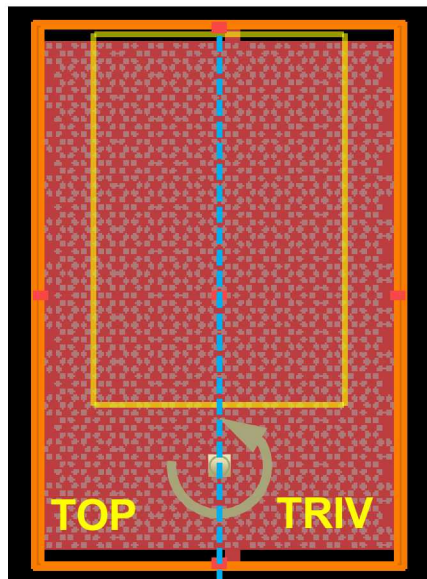
- Active topological structures based on III-N



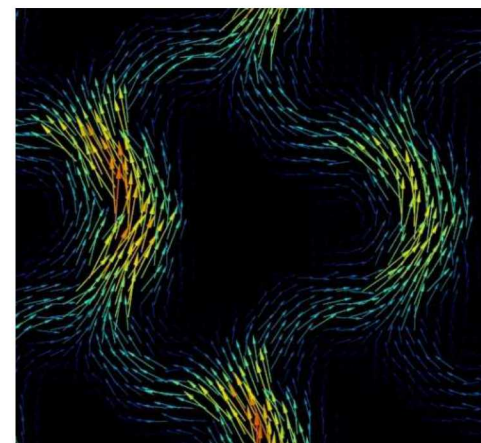
Thank you for your attention!

Extras ...

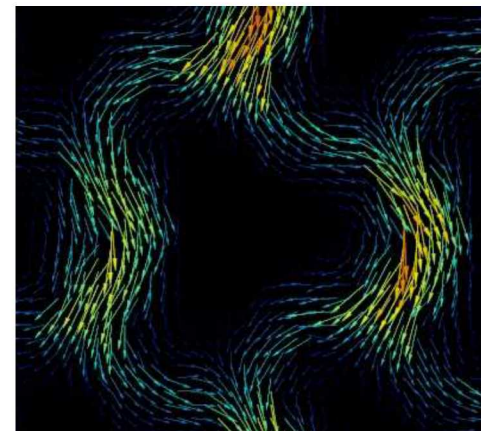
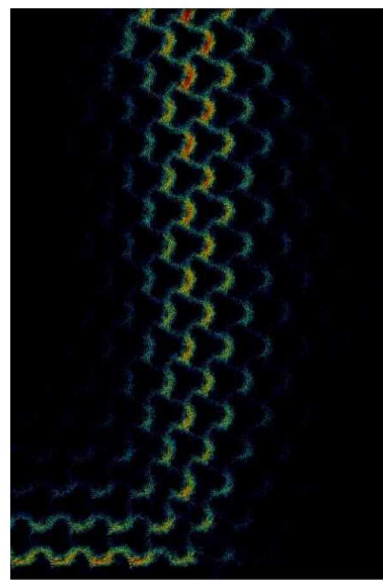
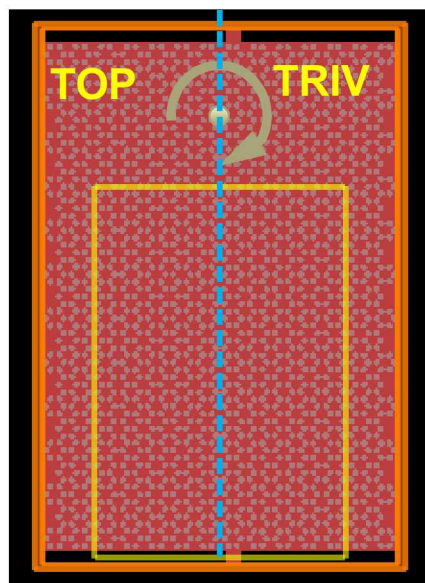
Unidirectional Propagation with Helical Sources



$$a/\lambda \sim 0.567$$

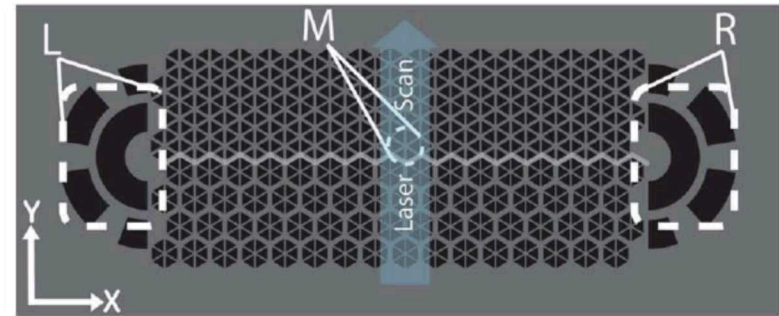
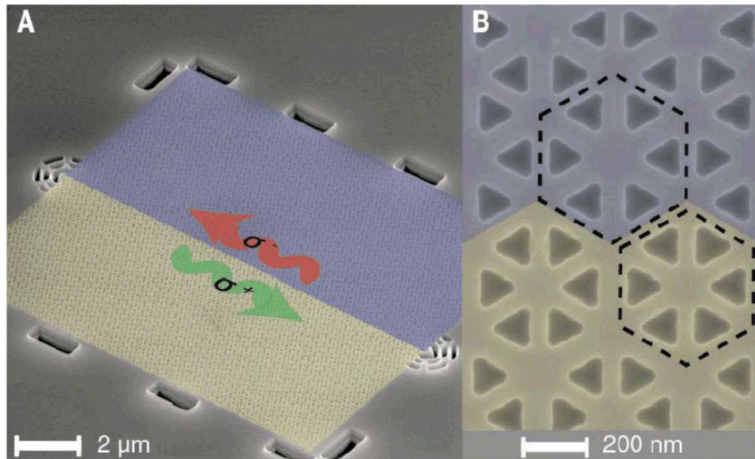


up



down

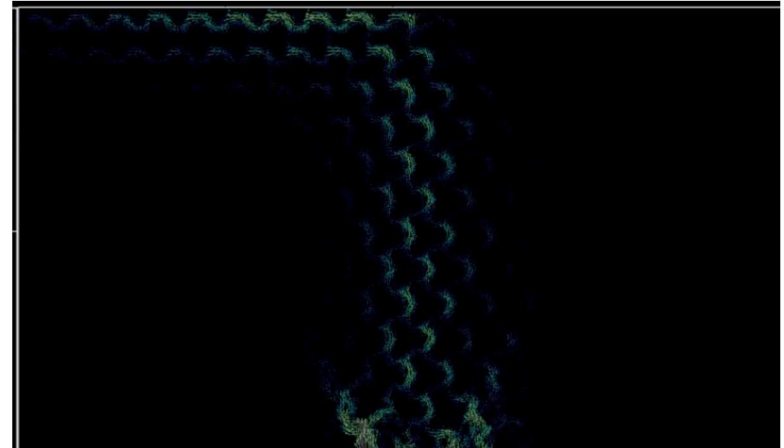
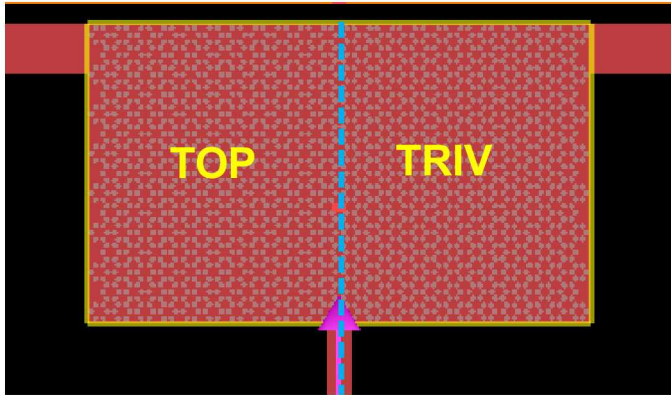
Quantum Dot based Helical Sources



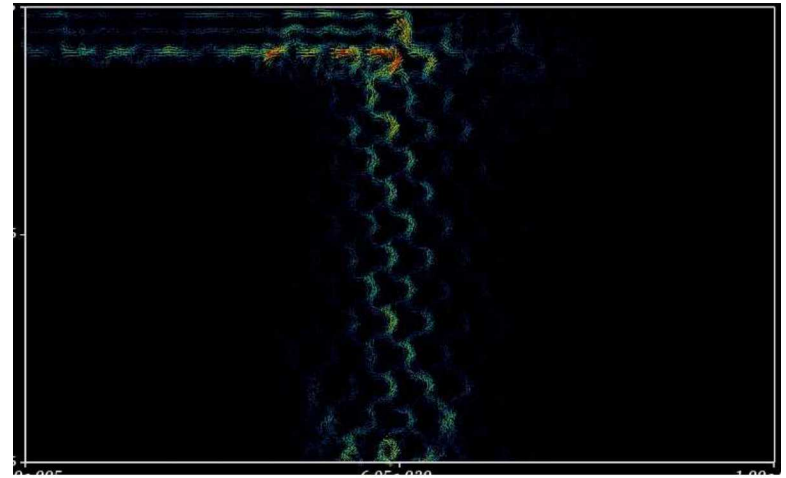
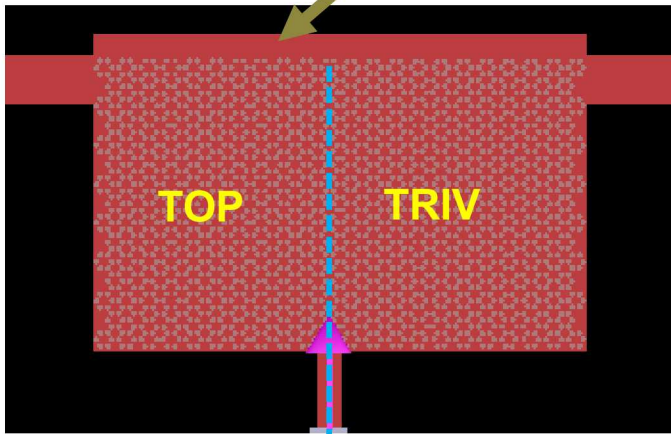
Barik, S., et al. (2018). "A topological quantum optics interface." Science **359**(6376): 666.

- Create a quantum dot inside the structure
- Apply high B field to split energy level as well as helicity
- Unidirectional propagation of single photon source
- Bandwidth difficult to demonstrate

What about a passive structure to manipulate light incident from elsewhere?

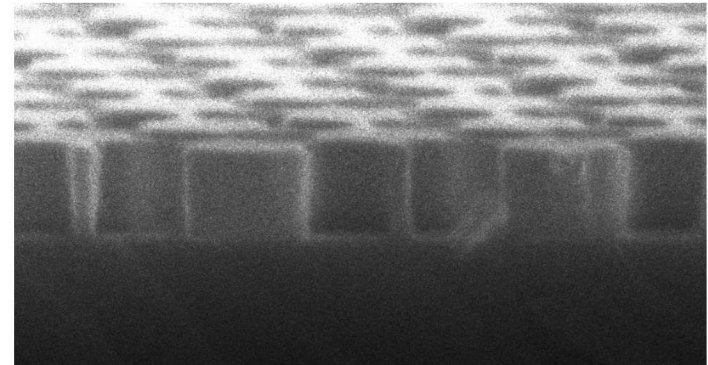
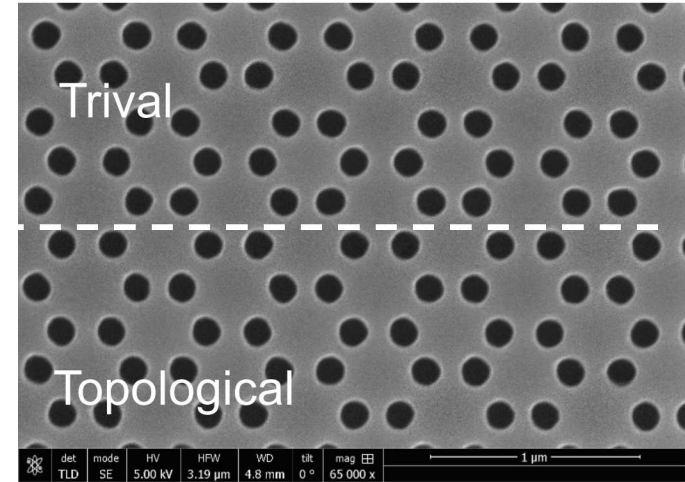
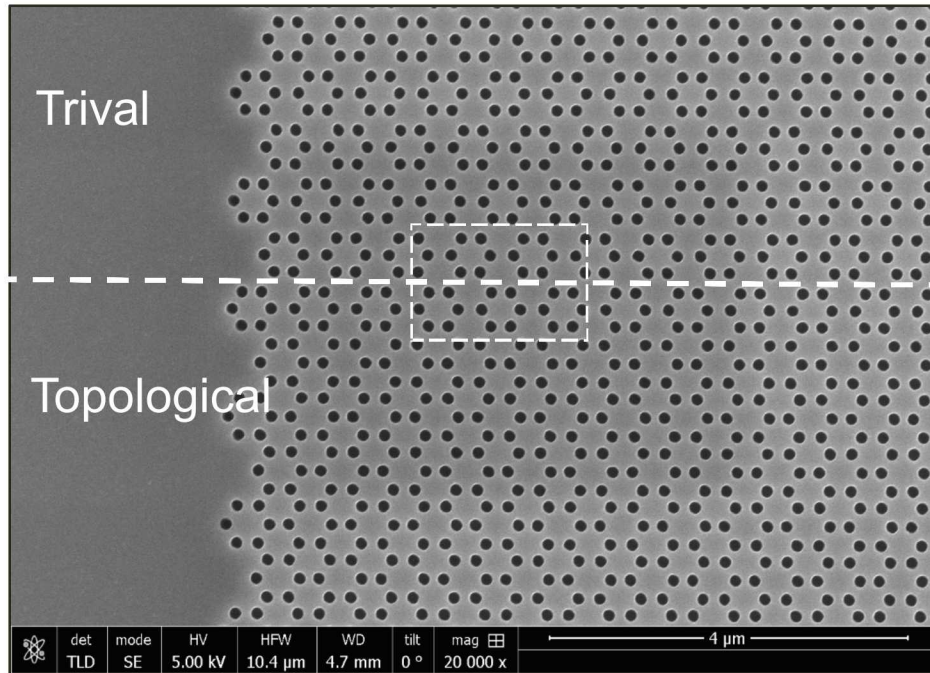


High index trivial medium

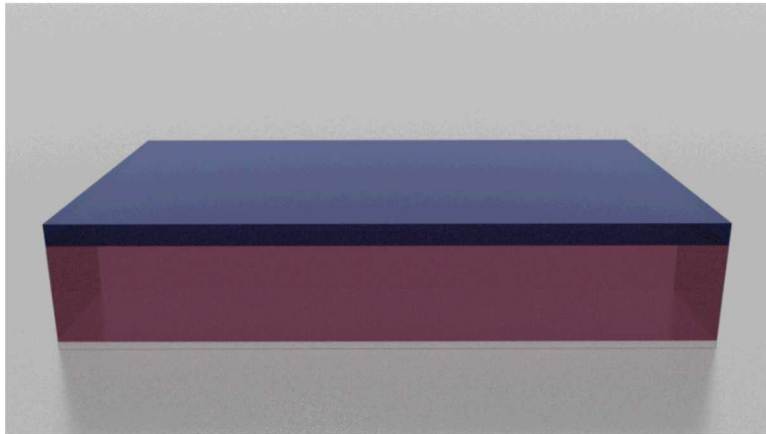


Fabrication on Silicon on Insulator (SOI) - Membrane

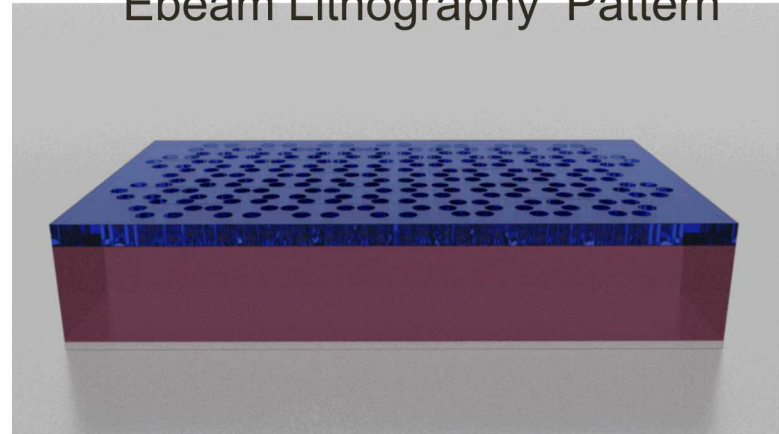
Topological/Trivial Interface structure



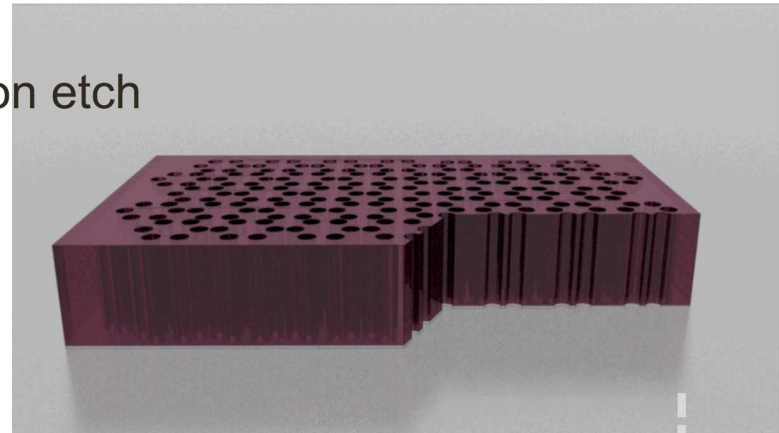
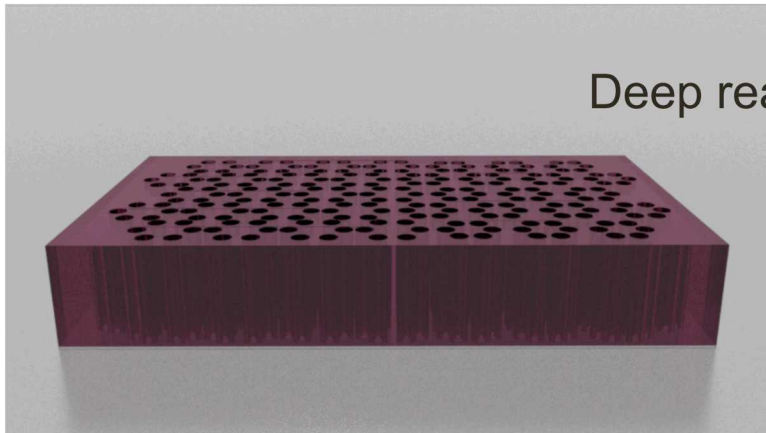
Fabrication on Thick Si using deep etch



Ebeam Lithography Pattern



Deep reactive Ion etch



This can be challenging fabricate and may not always be compatible with typical Si photonics designs.

Motivation: Topological Systems in Electronics

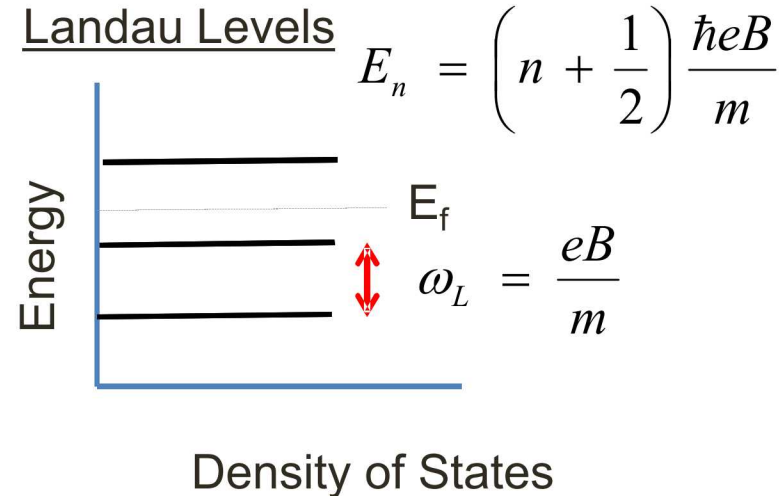
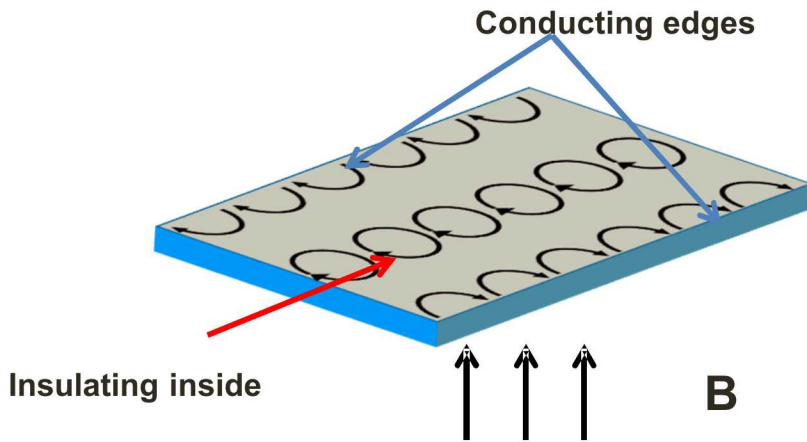
Electronic Topological Insulators : Systems exhibiting Quantum Hall Effect → 2DEGs

Time reversal symmetry is broken by applying magnetic (B) field

- Discrete highly degenerate Landau Levels
- Conducting edge states within insulator gap
- Topologically protected “one way” electronic transport



F. Duncan Haldane
(Physics Nobel Prize (2016))



It turns out appropriately designed photonic structures can exhibit similar topological properties too!



F. D. M. Haldane and S. Raghu, Phys. Rev. Lett. **100** (1) 013904 (2008).